

ABSTRACT

In a method of manufacturing a magnetic recording medium glass substrate, the step of polishing a first surface strengthening layer (101A) and a second surface strengthening layer (101B) polishes the first surface strengthening layer (101A) and the second surface strengthening layer (101B) so that both of a first polishing amount difference (P1) and a second polishing amount difference (P2) are not more than 0.10 μm , where the first polishing amount difference (P1) is the difference between the polishing amount of the first surface strengthening layer (101A) and the polishing amount of the second surface strengthening layer (101B) in a first circumferential region (C1) where a distance in a radial direction from the outer peripheral end surface (12) toward the rotation center (CP) is 2.5 mm, and the second polishing amount difference (P2) is the difference between the polishing amount of the first surface strengthening layer (101A) and the polishing amount of the second surface strengthening layer (101B) in a second circumferential region (C2) where a distance in a radial direction from the outer peripheral end surface (12) toward the rotation center (CP) is 6.5 mm.